

## VEGABAR series 80 HART

Version	Description
1.03.02-01	<b>Error corrections:</b> <ul style="list-style-type: none"> <li>Removed faulty status image (bugfix for registration)</li> </ul>
1.03.02-00	<b>Error corrections:</b> <ul style="list-style-type: none"> <li>Dynamic behaviour of the EDD improved for AMS</li> </ul>
1.03.01-02	<b>Error corrections:</b> <ul style="list-style-type: none"> <li>Possibility to limit adjustable units</li> </ul>
1.03.01-01	<b>Error corrections:</b> <ul style="list-style-type: none"> <li>Execution of methods with upcoming error status</li> </ul>
1.03.01-00	<b>New functions:</b> <ul style="list-style-type: none"> <li>Support of further HART Common Practice Commands</li> <li>Position correction with application "Density-compensated level" added</li> </ul> <b>Error corrections:</b> <ul style="list-style-type: none"> <li>Unit "Distance of sensors" corrected</li> <li>Selection list for HART variables adapted</li> </ul>
1.02.02-00	<b>Error corrections:</b> <ul style="list-style-type: none"> <li>Data type adaptation for Device Revision 3 for compatibility reasons</li> </ul>
1.02.01-00	<b>New functions:</b> <ul style="list-style-type: none"> <li>New application "Density-compensated level"</li> <li>Single layer correction in Slave mode</li> <li>Thermoshock suppression for Master and Slave can be adjusted separately</li> <li>Selectable menu languages for PLICSCOM extended by Chinese and Japanese</li> </ul> <b>Error corrections:</b> <ul style="list-style-type: none"> <li>Presentation of the handheld host is now more clearly</li> </ul>
1.01.03-00	<b>Error corrections:</b> <ul style="list-style-type: none"> <li>Data type adaptation for Device Revision 3 for compatibility reasons</li> </ul>
1.01.02-00	<b>Error corrections:</b> <ul style="list-style-type: none"> <li>Data type adaptation for Device Revision 2 for compatibility reasons</li> </ul>
1.01.01-00	<b>First DD version for adjustment</b>

## Versions history EDD



Version	Description
	<p><b>Applications:</b></p> <ul style="list-style-type: none"><li>• Process pressure</li><li>• by means of dielectric constant</li><li>• Flow</li><li>• Differential pressure (in conjunction with electronic differential pressure)</li><li>• Density (in conjunction with electronic differential pressure)</li><li>• Interface (in conjunction with electronic differential pressure)</li></ul>

### Legend:

Name	Description
Version	Compatibility version.Device Revision.DD Revision-Error correction version